

PTO/SB/08A (08-03)

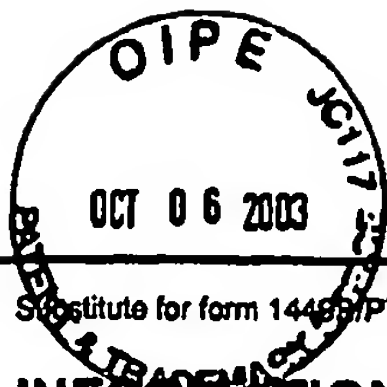
Substitute for form 1449A/PTO		Complete If Known			
		Application Number	10/632,662		
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (use as many sheets as necessary)		Filing Date	August 1, 2003		
		First Named Inventor	Staple, Bevan		
		Art Unit			
		Examiner Name			
Sheet	1	of	3	Attorney Docket Number	019930-003110US

U.S. PATENT DOCUMENTS+					
Examiner Initials*	Cite No. <sup>1</sup>	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number Kind Code <sup>2</sup> (if known)			
mc	A1	US-4,330,175	05-18-1982	Yohji Fujii et al.	
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Examiner Signature	<i>Michelle R. Connelly-Cuthbert</i>	Date Considered	3/4/04
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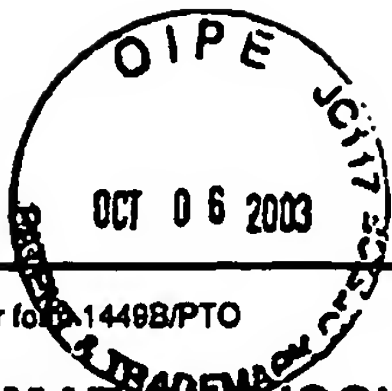
Substitute for form 1449 PTO <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (use as many sheets as necessary)		<b>Complete If Known</b>	
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NON PATENT LITERATURE DOCUMENTS			
Examiner Initials *	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
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MC	C12	KELLER, LUKE D. et al., <i>Fabrication And Testing Of Chemically Micromachined Silicon Echelle Gratings</i> , Applied Optics, March 1, 2000, Vol. 39, No. 7, pgs. 1094-1105.	
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Examiner Signature	<i>Michael R. Connolly</i>	Date Considered	3/4/04
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MC	C17	PHILLIPPE, P. et al., "Wavelength demultiplexer: using echelette gratings on silicon substrate," Applied Optics, Vol. 24, No. 7, 1 April 1985	
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MC	C27	VANKESSEL, P. et al., "A MEMS-Based Projection Display," Proceedings of the IEEE, Vol. 86, No. 8, August 1998; pp. 1687-1704	
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Examiner Signature	<i>Michelle R. Connolly</i>	Date Considered	3/4/04
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